

5     **We claim:**

1.     A printhead chip for an inkjet printhead, the printhead chip comprising  
a wafer substrate that incorporates drive circuitry, the wafer substrate defining a  
plurality of ink inlet channels; and  
10       nozzle arrangements positioned on the wafer substrate, each nozzle arrangement  
comprising  
a passive nozzle chamber structure that extends from the wafer substrate and  
bounds a respective ink inlet channel;  
a dynamic nozzle chamber structure that, together with the passive nozzle  
15    chamber structure, defines a nozzle chamber, and has a roof that defines the ink  
ejection port, the dynamic nozzle chamber structure being displaceable towards the  
wafer substrate into an actuated position and away from the wafer substrate into a rest  
position such that a drop of ink can be ejected from the ink ejection port, and  
an elongate micro-electromechanical actuator connected between the wafer  
20    substrate and the dynamic nozzle chamber structure, the actuator including a beam  
assembly that has an active beam of a conductive material, capable of thermal  
expansion, that defines a heating circuit and is connected to the drive circuitry and a  
passive beam that is interposed between the active beam and the wafer substrate such  
that, when the active beam receives an electrical signal from the drive circuitry, the  
25    active beam expands relative to the passive beam driving the dynamic nozzle structure  
into the actuated position to generate the drop of ink and when the signal is cut off  
subsequent cooling of the active beam causes the dynamic nozzle structure to move  
back to the rest position, facilitating a separation of the drop of ink.
- 30    2.     A printhead chip as claimed in claim 1, in which each dynamic nozzle chamber  
structure includes a skirt portion that depends from the roof inwardly of the passive nozzle  
structure, such that an edge of the skirt portion is proximate an edge of the passive structure in  
the rest position, the edges of the skirt portion and the passive structure being configured so  
that, when the nozzle chamber is filled with ink, a meniscus is defined between the edges, the

5 meniscus defining a fluidic seal as the dynamic structure is displaced between the actuated and rest positions.

3. A printhead chip as claimed in claim 2, in which the edge of each skirt portion is positioned between three and six microns above the wafer substrate, when the dynamic  
10 structure is in the rest position.

4. A printhead chip as claimed in claim 1, in which each beam assembly has an arm that interconnects the beams and the dynamic structure, so that displacement of the active and passive beams is transferred to the dynamic structure via the arm.  
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5. A printhead chip as claimed in claim 1, in which each passive beam is fixed, at one end, to the substrate, but insulated from the drive circuitry and fixed at an opposed end to the arm and each active beam is fixed, at one end, to the substrate to be electrically connected to the drive circuitry layer and also fixed at an opposed end to the arm..  
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6. A printhead chip as claimed in claim 1, in which each passive beam and each passive nozzle structure are of the same material.